



520.37698CX1

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

K. TAKAHASHI, et al.

Serial No.:

09/414,520

Filed:

October 8, 1999

Title:

A PLASMA PROCESSING APPARATUS AND A PLASMA
PROCESSING METHOD

Group:

1763

Examiner:

Rudy Zervigon

Confirm. No.:

3400

STATEMENT OF SUBSTANCE OF INTERVIEW**Mail Stop: ISSUE FEE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

November 14, 2005

Sir:

Appreciation is expressed to Examiner Zervigon for his courtesy during a personal interview conducted on October 11, 2005, in connection with the above-identified application.

During the course of the interview, Mr. Solomon pointed out the proposed amendments to claims 6, 15 and 16 and adding new claim 17. In the claims, the claim 6 limitation of "temperature control accuracy" to within $\pm 5^{\circ}\text{C}$ achieving improved etch rates (p. 31, Fig. 5,6) was combined, in light of the Satou reference. Agreement with respect to the claims was reached.

Further, the Examiner agreed to completely review the Amendment After Final Rejection filed October 3, 2005, and reconsider his ground of rejection and its maintainability.

If the Examiner believes that there are any points which may be clarified or otherwise disposed of, either by telephone discussion or by personal interview, the

Examiner is invited to contact Applicants' undersigned attorney at the number indicated below.

Please charge any shortage in fees due in connection with the filing of this paper to the Antonelli, Terry, Stout & Kraus, LLP Deposit Account, Deposit Account No. 01-2135 (Case No. 520.37698CX1), and please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By _____


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